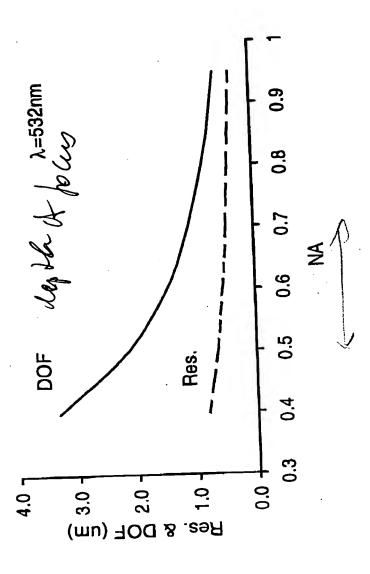


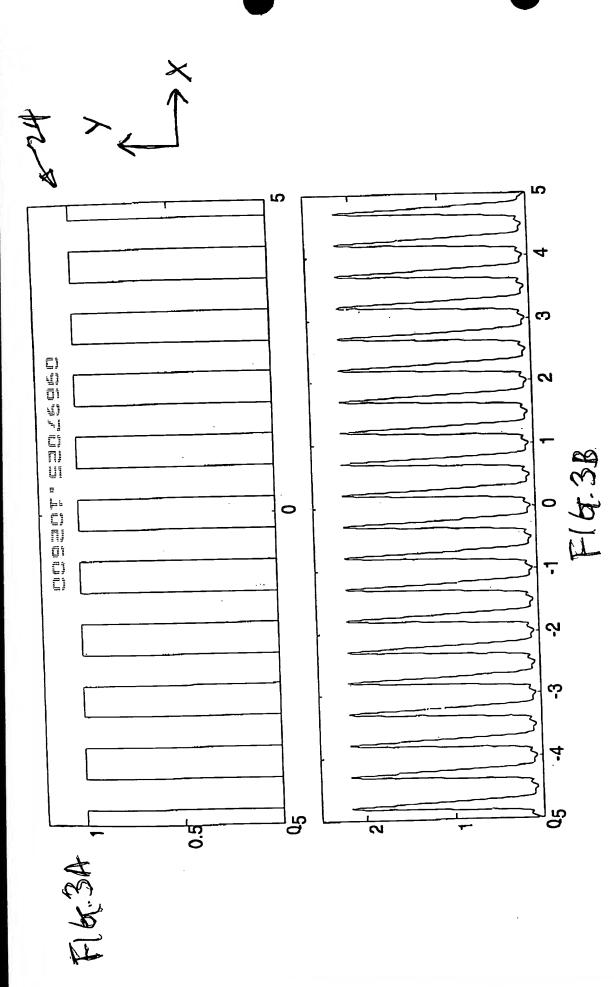
Figure 1. White light dark field system

1 (P)

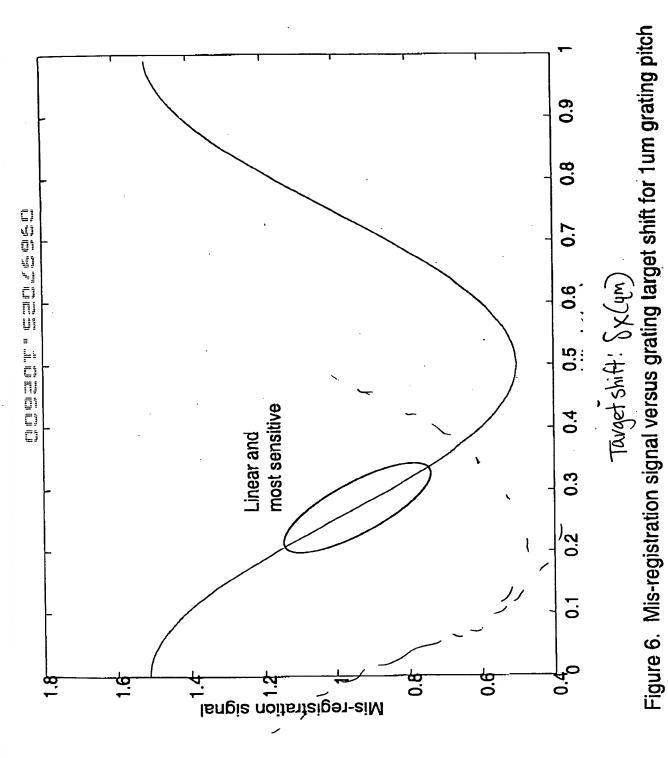


7.6

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Top: Overlay grating target; Bottom: White light dark field image of target

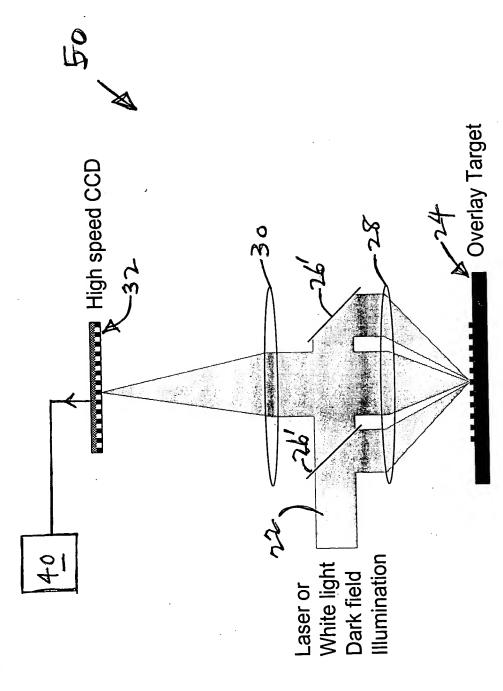


F19.4

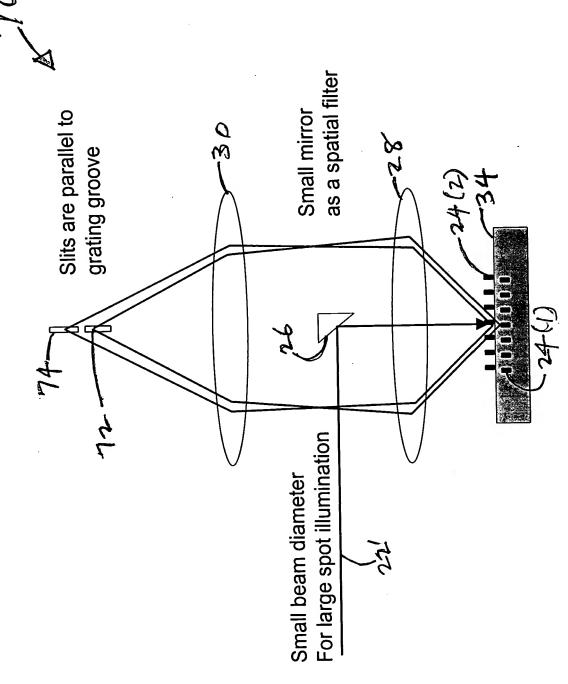
KIY.

ř

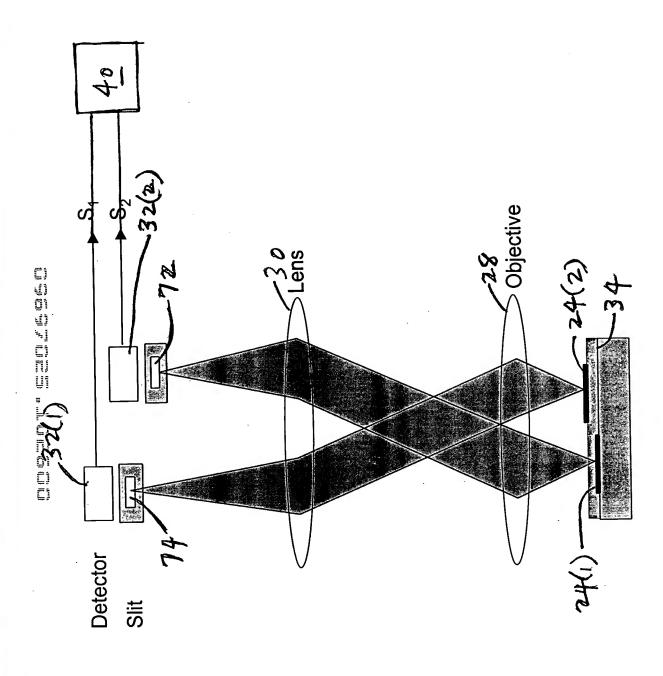
## Darkfield illumination for overlay error measurement



F16.5

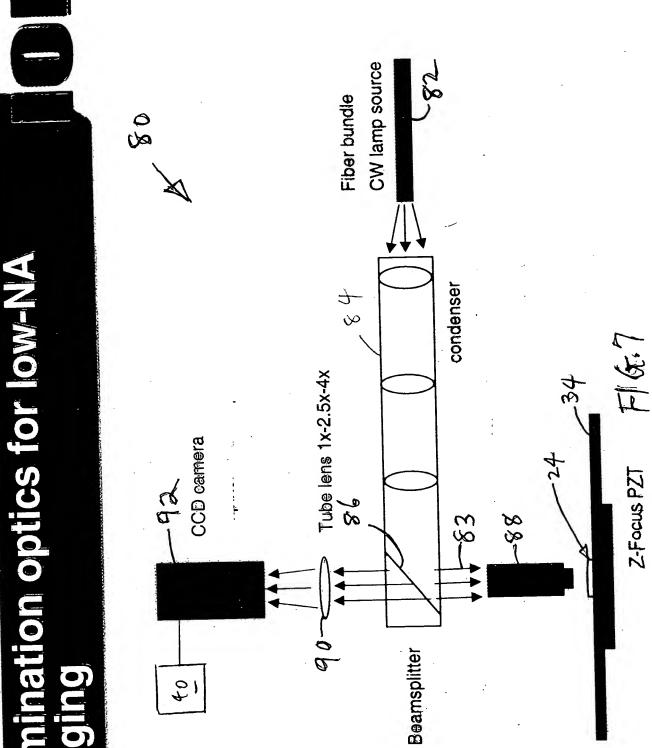


 $Fle_{-} (OA)$  Laser dark field with dual slit scanning, front view.



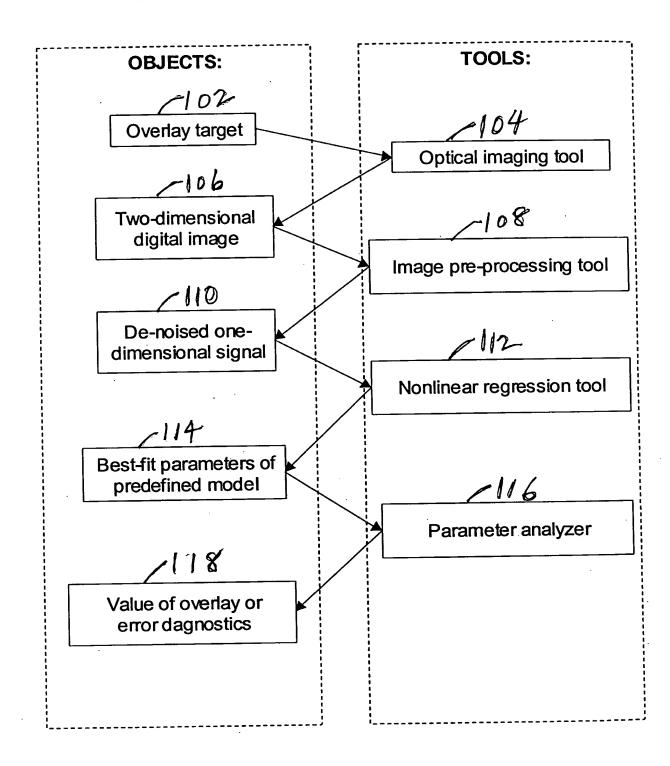
 $\Box f_{+} \oplus B$  Laser dark field with dual slit scanning, side view

## mination optics for low-NA

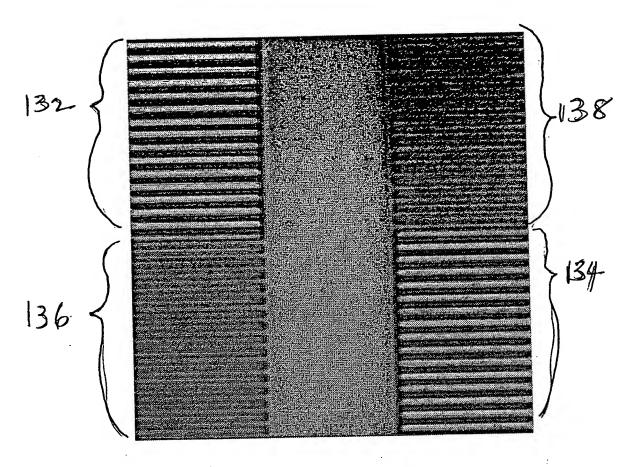


• Flor. 8

Flowchart: Objects and tools in this invention of overlay measurement



Example of a two-dimensional grating image I(x,y)



## Example of a two-dimensional box-in-box image I(x,y)

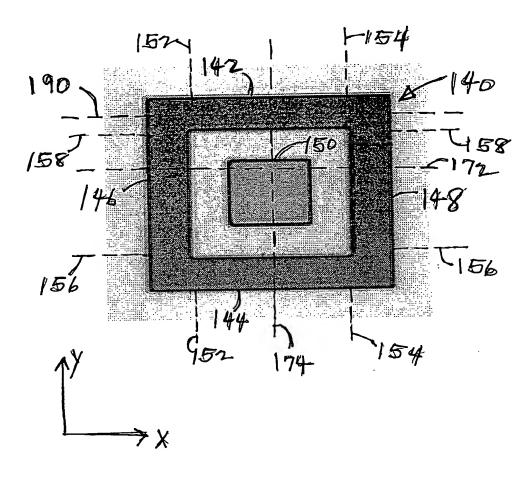
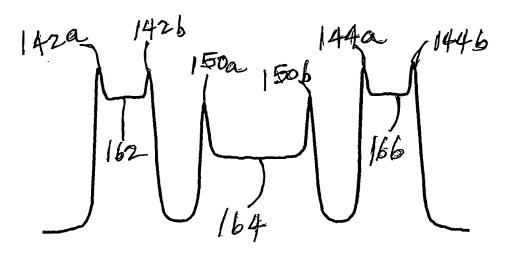
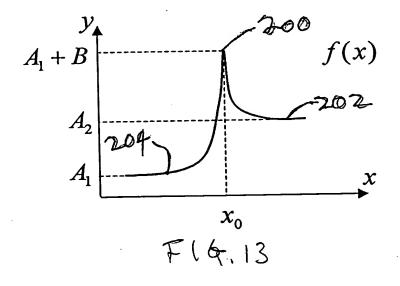
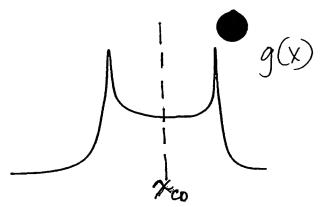


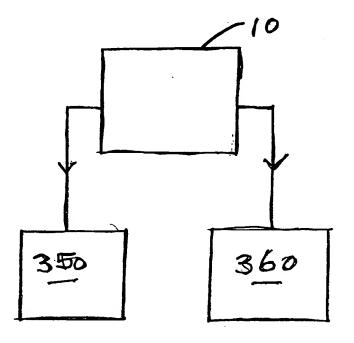
Fig. |2 Pre-processed box-in-box image converted into a de-noised one-dimensional signal I<sub>x</sub>(x).





F16.14





F14.15

